

SCREEN Launches SS-80EX Spin Scrubber Single Wafer Cleaning Equipment for 200 mm Semiconductor Wafers

Kyoto, Japan – December 11, 2015 – SCREEN Semiconductor Solutions Co., Ltd. (SCREEN SPE) has completed development of the SS-80EX spin scrubber, its new single wafer cleaning system for 200 mm semiconductor wafers. The SS-80EX is specifically designed for use in applications related to large-scale production of smartphones, in-vehicle systems and a wide range of other electronic devices. This new spin scrubber will be available from December 2015.

SS-80EX Spin Scrubber

Please download the photo from
<http://www.screen.co.jp/eng/spe/nl-photo/SPE151211E.zip>



In recent years, there has been a rapid increase in the demand for smartphones, in-vehicle systems and other electronic devices produced using 200 mm semiconductor wafers. Expansion of the Internet of Things (IoT) is also expected to accelerate, bringing closer an era of interactive connectivity in which all things possess communications functions.

These developments will naturally require the production of various types of electronic devices on a massive scale. To meet this demand, manufacturers of devices containing semiconductor components increasingly need high-throughput single wafer cleaning equipment that can adjust processing according to the surface conditions of individual wafers.

Against this background, SCREEN SPE has developed the new SS-80EX spin scrubber, the latest model in its SS series of single wafer cleaning equipment for 200 mm semiconductor wafers. The SS series has already established an unshakeable position in the industry thanks to its outstanding stability and reliability.

The SS-80EX inherits the SS series' same flexible configuration and wide range of cleaning tools developed for existing production goals and applications. It also features a fully redesigned transport system that enables approximately 160 wafers to be processed every hour. The SS-80EX likewise includes a completely revamped user interface that delivers major improvements in operability.

In addition, this system is equipped with a detachable chamber design that allows maintenance

procedures to be performed on stopped chambers while the others continue to operate. This setup dramatically reduces downtime, further enhancing the significant improvements in productivity made by the SS-80EX.

With its launch of the SS-80EX spin scrubber, SCREEN SPE intends to expand the business opportunities available in the 200 mm semiconductor equipment market. Demand is expected to grow in this segment with the increasing use of smartphones and in-vehicle systems as well as the acceleration of the Internet of Things. SCREEN SPE will continue to create products that meet the diverse needs of the semiconductor industry, with the goal of promoting its overall expansion.

Note:

- This system will be introduced at SEMICON Japan 2015 to be held at Tokyo Big Sight in Ariake, Tokyo from December 16 (Wednesday) to 18 (Friday).

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